

# SCIENTIFIC REPORTS

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## Vertical WS<sub>2</sub>/SnS<sub>2</sub> van der Waals Heterostructure for Tunneling Transistors

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Van der Waals heterostructures composed of two-dimensional (2D) transition metal dichalcogenides (TMD) materials have stimulated tremendous research interest in various device applications, especially in energy-efficient future-generation electronics. Such ultra-thin stacks as tunnel junction theoretically present unprecedented possibilities of tunable relative band alignment and pristine interfaces, which enable significant performance enhancement for steep-slope tunneling transistors. In this work, the optimal 2D-2D heterostructure for tunneling transistors is presented and elaborately engineered, taking into consideration both electric properties and material stability. The key challenges, including band alignment and metal-to-2D semiconductor contact resistances, are optimized separately for integration. By using a new dry transfer technique for the vertical stack, the selected WS<sub>2</sub>/SnS<sub>2</sub> heterostructure-based tunneling transistor is fabricated for the first time, and exhibits superior performance with comparable on-state current and steeper subthreshold slope than conventional FET, as well as on-off current ratio over 10<sup>6</sup> which is among the highest value of 2D-2D tunneling transistors. A visible negative differential resistance feature is also observed. This work shows the great potential of 2D layered semiconductors for new heterostructure devices and can guide possible development of energy-efficient future-generation electronics.

Atomically thin two-dimensional (2D) semiconductors beyond graphene have emerged as one of the most promising material candidate for next generation electronic devices because of their sizable bandgap<sup>1–6</sup>. Recently, van der Waals heterostructures composed of 2D transition metal dichalcogenides (TMD) semiconductor with a broad range of material diversity have gained tremendous research interest in various device applications, especially in steep-slope tunneling transistors due to their superior properties beyond traditional bulk materials limits<sup>1,2</sup>. On one hand, van der Waals interactions enable the possibility for diverse heterostructures of highly distinct materials without the constraints of lattice matching, which is different from the covalent bonding in traditional bulk materials<sup>1–4</sup>. On the other hand, the dangling-bond-free interfaces of van der Waals heterostructure could mitigate the parasitic trap-assisted tunneling induced by interface states in traditional III-V-based tunneling heterojunction<sup>1–7</sup>. Moreover, for 2D-based tunneling heterojunctions, the relative band alignment can be modulated through electrostatic gating due to the van der Waals gap between the neighboring layers, theoretically suggesting that the type-II band alignment in the off-state could be modulated to type-III band alignment in the on-state for high drive current<sup>8</sup>. Consequently, tunneling transistors based on van der Waals heterostructures are expected to realize low leakage current, ultra-steep slope and high on/off current ratio simultaneously, which has been confirmed by lots of theoretical works and shows the great potential in low power electronics<sup>9–12</sup>. However, only a few experimental works have been reported regarding the tunneling transistors based on van der Waals heterostructures. Black Phosphorus (BP)/MoS<sub>2</sub> tunneling transistors have been fabricated, while its high tunnel barrier ( $E_{\text{beff}}$ ) of approximately 0.5 eV at the heterojunction requires relatively large voltage to modulate the band alignment, demonstrating the limited on/off current ratio ( $\sim 10^4$  at 3 V voltage range)<sup>13</sup>. Besides, BP material is unstable in the air, which would also cause the degradation of device performance<sup>14–16</sup>. Reported dual-gated tunneling transistors utilizing WSe<sub>2</sub>/MoS<sub>2</sub> also exhibited the unsatisfactory on/off current ratio of 10<sup>3</sup> due to the large  $E_{\text{beff}}$ <sup>8</sup>. As an

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improvement,  $\text{WSe}_2/\text{SnSe}_2$  tunneling transistors with  $E_{\text{beff}}$  lowered to 0.4 eV were reported and the on/off current ratio is remarkably enhanced<sup>17</sup>. However,  $\text{SnSe}_2$  is very unstable in the ambient environment, and can be easily oxidized<sup>18</sup>. Besides the  $E_{\text{beff}}$  and stability, the metal-to-2D semiconductor contact resistances would also severely limit the performance of 2D-based transistors<sup>19</sup>. Therefore, in spite of the optimism created by theoretical works, experimental optimization and demonstration of 2D-2D tunneling transistors with both high on/off current ratio and high material stability are still in urgent need.

In this work, the stable  $\text{WS}_2/\text{SnS}_2$  van der Waals heterostructure with theoretically 0.02 eV  $E_{\text{beff}}$  is considered for the first time and selected as the optimal material platform for tunneling transistors. This optimal heterostructure is further experimentally demonstrated, and the  $\text{WS}_2$  and  $\text{SnS}_2$  serve as the p-type source layer and the n-type channel and drain layer, respectively. The key challenge of metal-to-2D semiconductor contact is further optimized for integration. Based on the physical insight into the metal/2D interfaces, work-function- and thickness-engineering are conducted for p-type  $\text{WS}_2$  and n-type  $\text{SnS}_2$  respectively to reduce the contact resistances. Based on a novel dry transfer technique for vertical heterostructure stack, the bottom-gated  $\text{WS}_2/\text{SnS}_2$  tunneling transistor is fabricated and shows the on/off current ratio exceeding  $10^6$ , which is among the highest in the reported tunneling transistors. Compared with the conventional FET, comparable on-state current and steeper subthreshold slope (SS) are also obtained. The tunnel behaviors are further confirmed by low temperature measurements, and a visible negative differential resistance feature is observed. This work shows the great potential of van der Waals heterostructure for tunneling devices and future-generation energy-efficient electronics.

## Results and Discussion

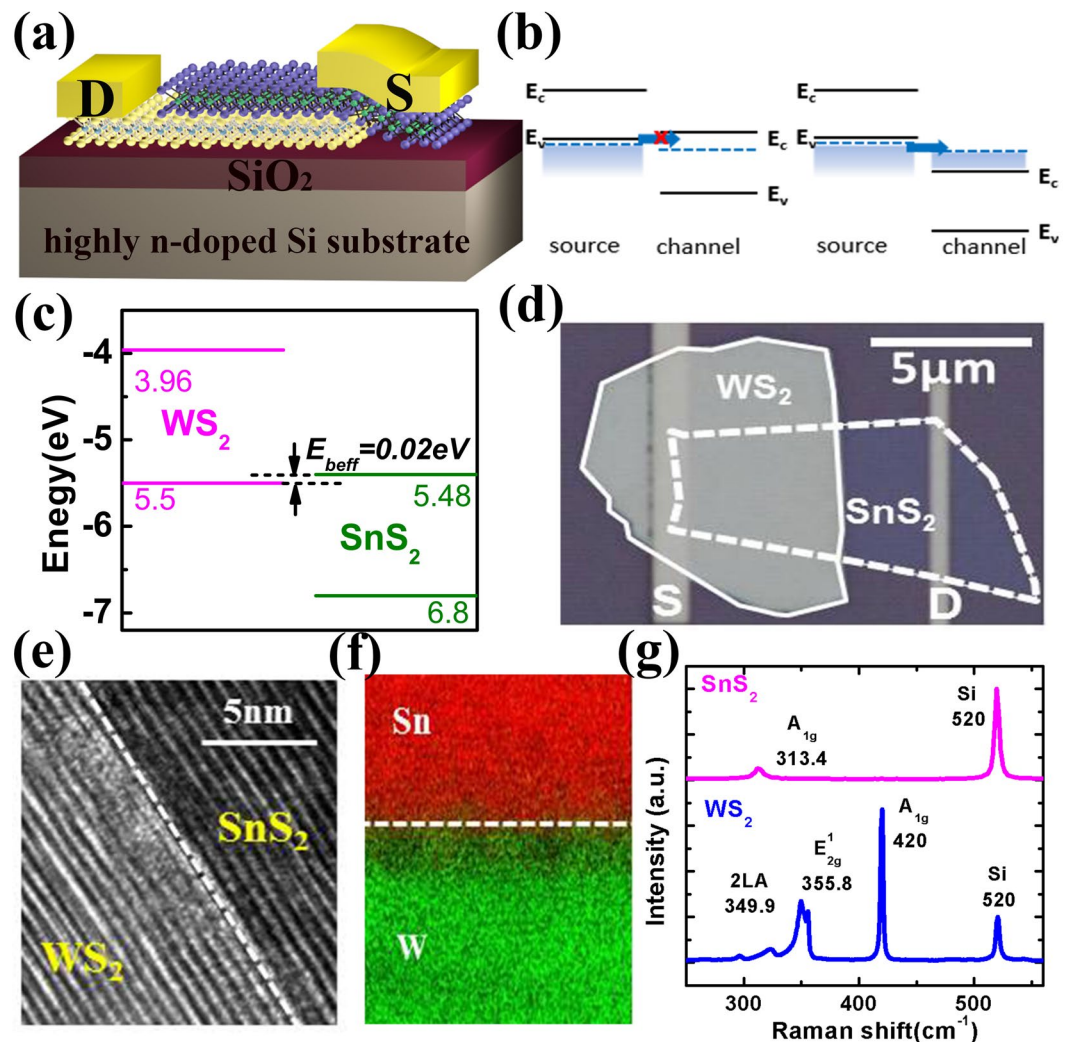
Figure 1a shows the schematic structure of bottom-gated vertical tunneling transistors based on the van der Waals heterostructure in this work. The  $\text{SiO}_2$  and highly n-doped Si are used as the gate dielectric and bottom gate, respectively. The channel layer is designed to be under the source layer, and the electric potential and carrier concentration of the channel layer are modulated by the bottom gate. The band alignment of the van der Waals heterostructure is designed to be type-II, in which the conduction band of the channel layer is above the valence band of the source layer. Figure 1b illustrates the operation mechanism of this n-type tunneling transistor. In the off-state, electrons in the valence band of the source layer cannot tunnel into the conduction band of the channel layer, since there is no tunneling window. As the bottom gate bias increases, the conduction band energy ( $E_C$ ) of the channel layer begins to be lower than the valence band energy ( $E_V$ ) of the source layer, and the tunnel current across the source layer/channel layer heterostructure will increase accordingly, exhibiting n-type characteristics. The band alignment can be tuned from type-II towards type-III due to the van der Waals gap, which would enhance the on/off current ratio of the transistor.

Taking into consideration of both device performance and material stability, the optimal heterostructure for tunneling transistor is selected by the following principles. First, from the perspective of on/off current ratio, the tunnel barrier  $E_{\text{beff}}$  should be considerably reduced so that low voltage is required to modulate the band alignment from type-II to type-III<sup>17</sup>. Second, tunneling electrons with smaller effective mass is beneficial for the higher tunnel efficiency and the higher tunnel current<sup>20</sup>. Third, according to our previous work, the lower density-of-state (DOS) of the channel layer would result in the better output characteristics of tunneling transistors with the smaller onset voltage and the better current saturation behavior<sup>21</sup>. At last, the stability of building materials to form heterostructures in ambient environment should also be taken into account for better device stability and reliability. Based on the above design rules, and according to the band structures of various 2D semiconductors from ab initio calculations<sup>22,23</sup>, p- $\text{WS}_2/\text{n-SnS}_2$  heterostructure stands out as the superior material platform for tunneling transistor. The  $E_{\text{beff}}$  in this near broken-gap heterostructure can be lowered to 0.02 eV theoretically, as shown in Fig. 1c. Meanwhile, the effective mass of electron in  $\text{WS}_2$  is relatively small compared to other metal dichalcogenides, and the low DOS of the channel layer  $\text{SnS}_2$  can improve the output characteristics of tunneling transistors in the meantime<sup>24,25</sup>. More importantly,  $\text{WS}_2$  and  $\text{SnS}_2$  is proved to possess great stability in ambient air<sup>26,27</sup>.

Figure 1d shows the optical image of a fabricated  $\text{WS}_2/\text{SnS}_2$  tunneling transistor in this work. The bottom-gate dielectric of 300 nm-thick  $\text{SiO}_2$  was firstly grown on the highly n-doped Si substrate. Then,  $\text{SnS}_2$  and  $\text{WS}_2$  sheets were vertically stacked to form the van der Waals heterostructure, and after that, source and drain contacts were sequentially defined by electron beam lithography, electron beam evaporation and lift-off process.

For the heterostructure preparation, the  $\text{SnS}_2$  crystals were then grown by chemical vapor transport method and mechanically exfoliated onto the  $\text{SiO}_2/\text{Si}$  substrate. The  $\text{WS}_2$  sheet was stacked upon  $\text{SnS}_2$  using a novel dry transfer process to avoid liquid contamination (see the dry transfer process in Supplementary Fig. S1), and the heterostructure was formed via van der Waals interaction. Figure 1e shows the high-resolution scanning TEM (STEM) image of the  $\text{WS}_2/\text{SnS}_2$  heterostructure, confirming the clean interface obtained by the dry transfer process. The measured interlayer distance of  $\text{WS}_2$  is 0.66 nm and that of  $\text{SnS}_2$  is 0.6 nm, which agree well with values reported in refs<sup>28–30</sup>. Energy-dispersive X-ray spectroscopy (EDS) composition analysis exhibits the sharp boundary between W and Sn, as shown in Fig. 1f. Raman spectra of these two sheets are shown in Fig. 1g and Raman peaks of both materials are clearly identified. The thicknesses of  $\text{WS}_2$  and  $\text{SnS}_2$  in this device are 23 nm and 4 nm, respectively. The characteristic Raman peaks of  $\text{WS}_2$  and  $\text{SnS}_2$  can be distinctly observed.  $\text{WS}_2$  shows the 2LA peak at  $349.9\text{ cm}^{-1}$ ,  $E_{2g}$  peak at  $355.8\text{ cm}^{-1}$ , and  $A_{1g}$  peak at  $420\text{ cm}^{-1}$ . The  $A_{1g}$  peak of  $\text{SnS}_2$  is observed at  $313.4\text{ cm}^{-1}$ .

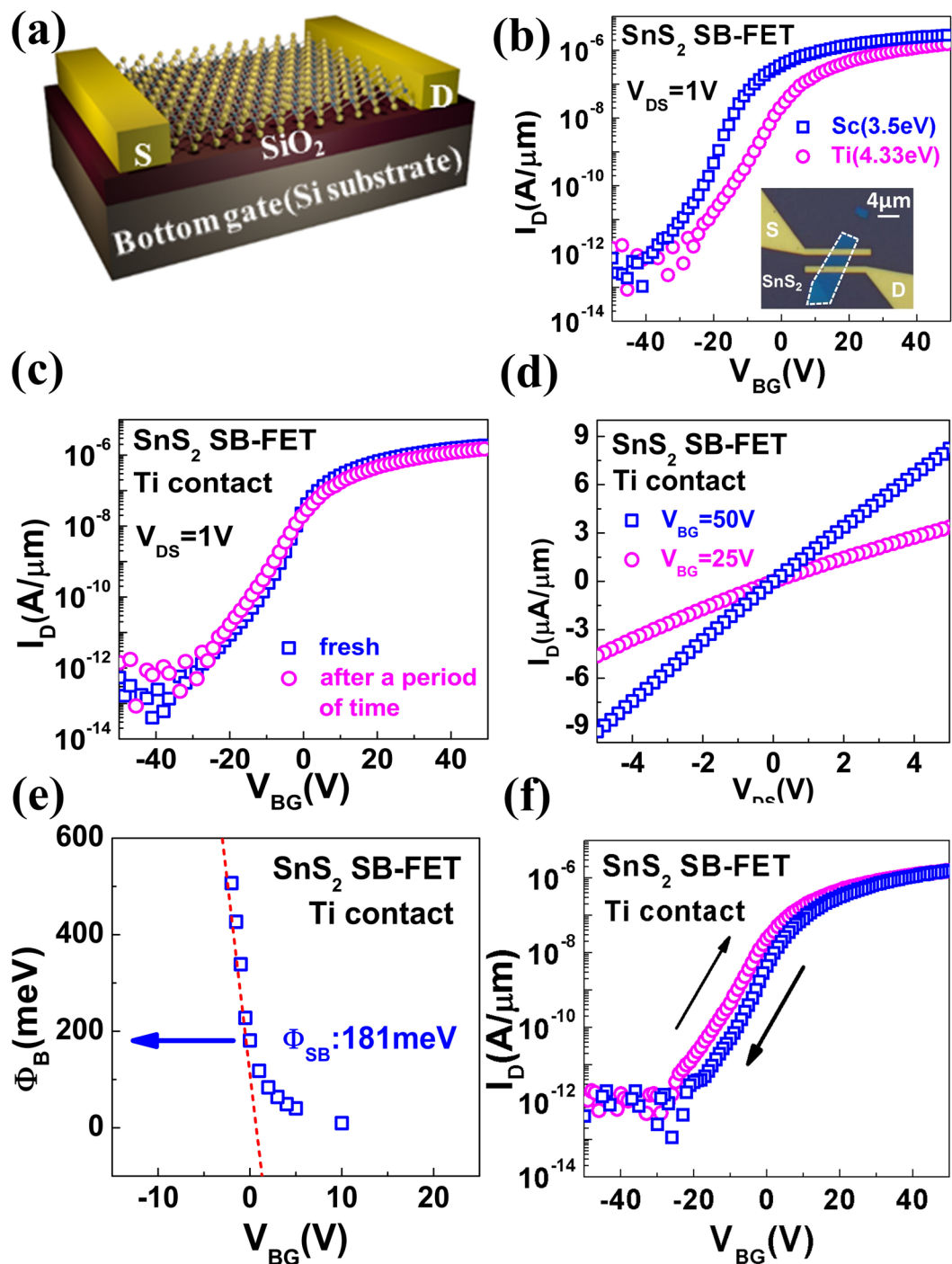
In order to reduce the contact resistances for better device performance, contact-engineering is conducted for p-type  $\text{WS}_2$  and n-type  $\text{SnS}_2$ , separately. To date, contacts of metal-to-2D semiconductors in the majority of reported metal dichalcogenide transistors are Schottky contacts instead of Ohmic contacts due to the difficulty of heavy doping in thin 2D semiconductors, which is also the case in  $\text{WS}_2$  and  $\text{SnS}_2$ <sup>28,31–33</sup>. In principle, low work functions ( $W_m$ ) of contact metals lead to the small Schottky barrier (SB) height for electrons, and high work function metals are beneficial for low hole barriers. In order to investigate the SB height at metal-to-2D



**Figure 1.** (a) Schematic view of the bottom-gated vertical tunneling transistor based on 2D semiconductors. Vertical tunneling occurs across the overlap region between p-type layer and n-type layer. (b) Band alignment in the off-state (left). There is no tunneling window between the valence band of the source layer and the conduction band of the channel layer. Band alignment in the on-state (right). The electric potential and carrier concentration of the channel layer are modulated by the bottom gate, and the tunneling window exists in which electrons can tunnel from the valence band of the source layer to the conduction band of the channel layer. (c) Band diagram of the WS<sub>2</sub>/SnS<sub>2</sub> heterostructure with E<sub>beff</sub> of 0.02 eV. (d) The optical microscope image of the fabricated n-type WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistor. (e) High-resolution STEM image and (f) EDS mapping of the WS<sub>2</sub>/SnS<sub>2</sub> heterostructure. A clean and sharp interface is obtained. (g) Raman characterization of WS<sub>2</sub> and SnS<sub>2</sub> sheets used for tunneling transistors.

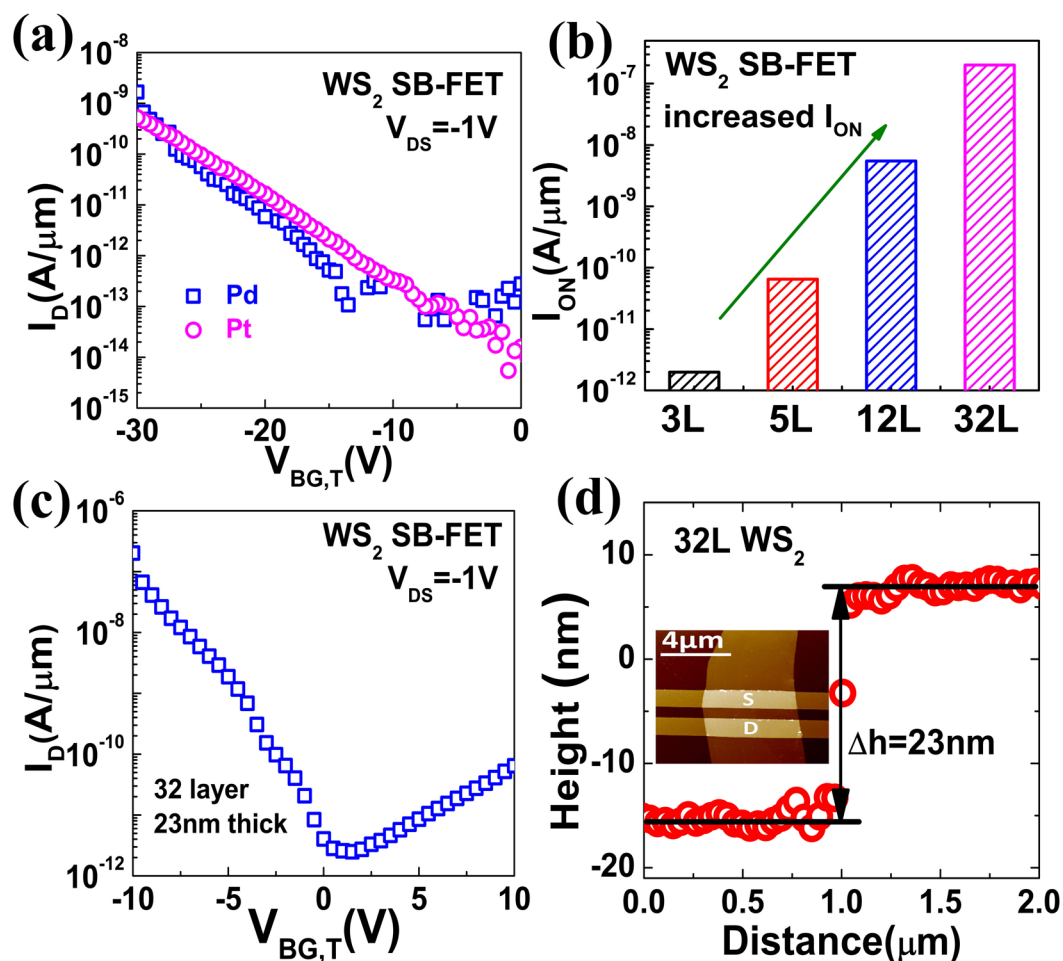
semiconductor contacts, bottom-gated SnS<sub>2</sub> and WS<sub>2</sub> SB-FETs were fabricated and characterized firstly as shown in Fig. 2a. For SnS<sub>2</sub> SB-FETs, Ti (W<sub>m</sub> = 4.33 eV) and Sc (W<sub>m</sub> = 3.5 eV) were adopted for realizing n-type contacts due to their low W<sub>m</sub><sup>34</sup>. Both Ti- and Sc-contacted SnS<sub>2</sub> SB-FETs exhibit n-type transistor behaviors (Fig. 2b). Yet compared with Ti, Sc would be easily oxidized in the air, resulting in severe degradation of transfer characteristics for Sc-contacted SB-FETs over time (Fig. 2c and Supplementary Fig. S2). Therefore, Ti with the better stability is chosen as the electrode for contacts to SnS<sub>2</sub> in the n-type tunneling transistors in this work. Figure 2d shows the measured output characteristics of Ti-contacted SB-FETs, and the linear dependence of current on drain voltage further confirms the low contact resistance at Ti/SnS<sub>2</sub> interfaces<sup>33</sup>. The extracted Schottky barrier height is as low as 0.181 eV (Fig. 2e), and the detailed extraction method can be seen in Supplementary Fig. S3. Additionally, no significant hysteresis is observed in the transfer characteristics of SnS<sub>2</sub> FET with Ti contacts (Fig. 2f).

Apart from n-type contacts to SnS<sub>2</sub>, the resistance of p-type contacts to WS<sub>2</sub> was also investigated. High work function metals, Pd (W<sub>m</sub> = 5.12 eV) and Pt (W<sub>m</sub> = 5.65 eV), were chosen as the metal electrodes to realize low-resistance p-type contacts<sup>34</sup>. Figure 3a shows the measured transfer characteristics of WS<sub>2</sub> SB-FETs. Although there is a significant difference (0.53 eV) of work functions between Pd and Pt, hole current in the Pd-contacted SB-FET is comparable to that in Pt-contacted device, indicating the strong Fermi-level pinning at the metal/WS<sub>2</sub> interface. In order to suppress Fermi-level pinning at the metal-to-2D material interface, inserting a thin layer of



**Figure 2.** Optimization of n-type contact for SnS<sub>2</sub>. (a) Schematic view of bottom-gated SnS<sub>2</sub> or WS<sub>2</sub> SB-FETs. (b) Measured transfer characteristics of n-type SnS<sub>2</sub> SB-FETs using Ti and Sc as contacts (V<sub>BG</sub> is the voltage applied to the highly n-doped Si substrate). Inset is the optical microscope image of SnS<sub>2</sub> SB-FET. (c) Transfer characteristics of SnS<sub>2</sub> SB-FET with Ti contacts after a period of time, (d) Measured output characteristics of n-type SnS<sub>2</sub> SB-FETs using Ti contacts. Linear dependence of I<sub>D</sub> on V<sub>DS</sub> indicates low contact resistance. (e) Extracted SB height for the Ti-to-SnS<sub>2</sub> contact. (f) Measured hysteresis characteristics of the SnS<sub>2</sub> SB-FET with Ti contacts, showing no significant hysteresis.

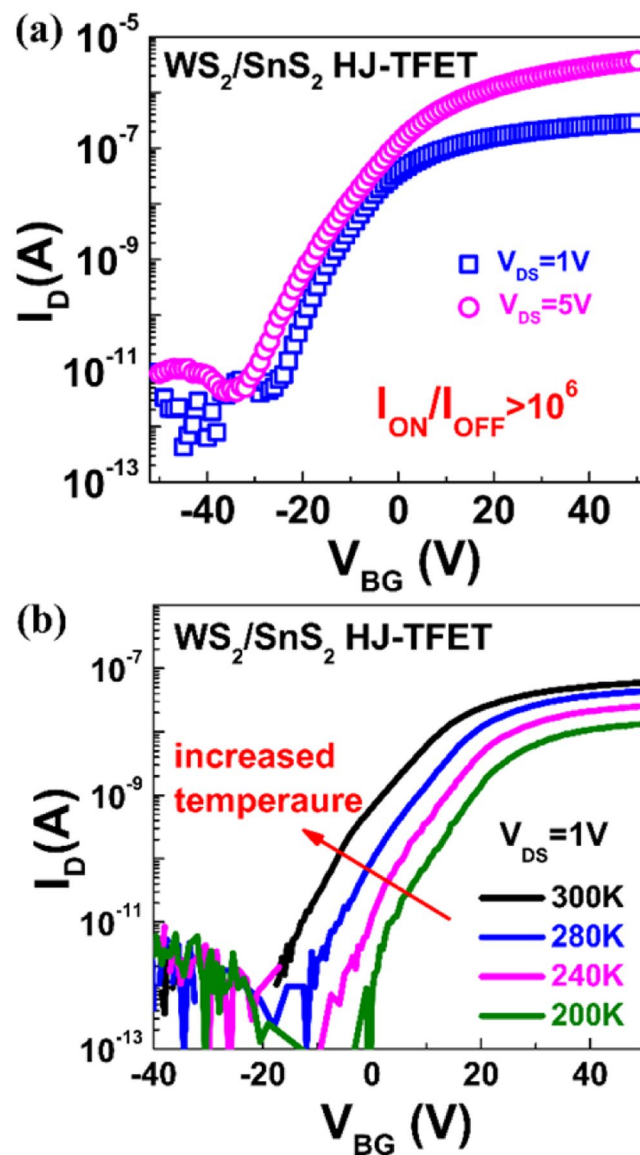
substoichiometric molybdenum trioxide (MoO<sub>x</sub>) between metal and 2D materials has been verified as an effective way to facilitate hole injection, which can be attributed to the high work function of MoO<sub>x</sub> and its excellent interface properties with 2D materials<sup>31</sup>. However, the work function of MoO<sub>x</sub> is very sensitive to ambient gas exposure, and thus the device performance will degrade in the air. Therefore, a novel approach is proposed in this work to reduce the SB height for holes at metal-to-WS<sub>2</sub> contacts. As we know, the bandgaps of 2D semiconductors are thickness-sensitive due to the influence of quantum confinement effect<sup>23</sup>. According to results from ab



**Figure 3.** Optimization of p-type contact for WS<sub>2</sub>. (a) Measured transfer characteristics of p-type WS<sub>2</sub> SB-FETs using Pd and Pt contacts ( $V_{BG,T} = V_{BG} - V_{\text{onset(Pt)}}$ ,  $V_{\text{onset(Pt)}}$ : the onset voltage at which hole current begins to increase in the Pt-contacted SB-FET). Similar currents are observed in these two devices. (b) Dependence of on-state current density on WS<sub>2</sub> thickness in WS<sub>2</sub> SB-FETs. The on-state hole current increases with the number of WS<sub>2</sub> layers. (c) Measured transfer characteristics of SB-FET with 23 nm-thick WS<sub>2</sub>. Large hole current in the on-state indicates the low resistance of fabricated p-type contacts. (d) AFM height profile of the 32-layer WS<sub>2</sub> sheet. Inset is the corresponding AFM image of fabricated devices.

initio calculations, as the thickness of WS<sub>2</sub> layers increases, the valence band moves upward while the position of conduction band remains nearly unchanged<sup>23</sup>. As a consequence, the SB height for holes can be decreased with thicker WS<sub>2</sub>. In this work, SB-FETs with different numbers of WS<sub>2</sub> layers were fabricated and Fig. 3b shows the corresponding hole currents. As the number of WS<sub>2</sub> layers increases from 3 to 12, hole currents are increased by three decades. When the thickness of WS<sub>2</sub> layers is increased to 23 nm, WS<sub>2</sub> p-type SB-FET exhibits high  $I_{ON}$  exceeding  $0.2 \mu\text{A } \mu\text{m}^{-1}$  (Fig. 3c), suggesting low resistance of fabricated p-type contacts. Figure 3d shows the atomic force microscope (AFM) image of the 23 nm-thick WS<sub>2</sub> SB-FET, and the height difference between the WS<sub>2</sub> sheet and the substrate.

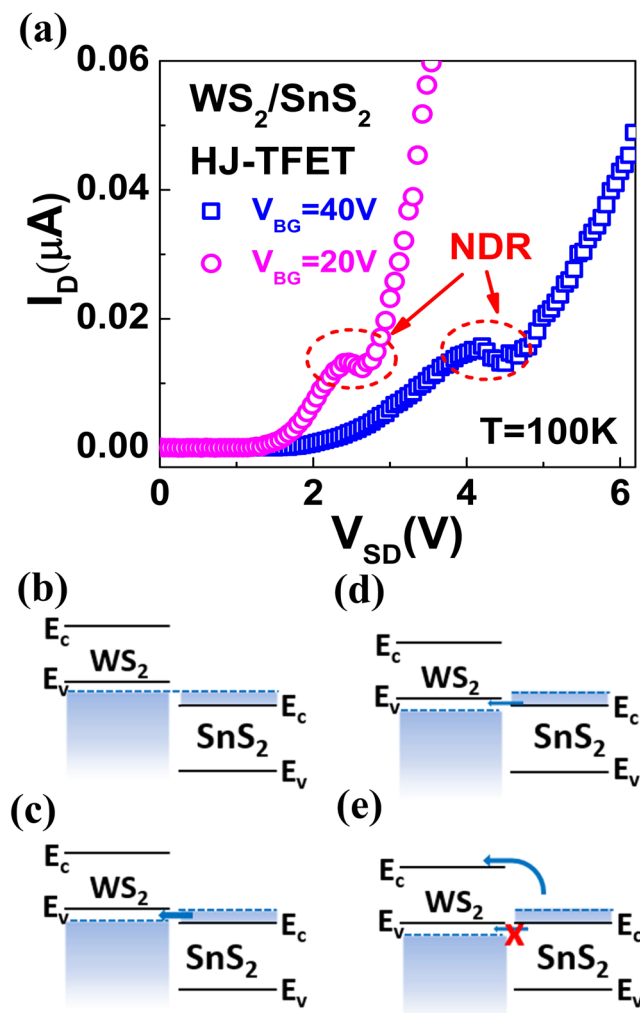
Based on the optimized n-type and p-type contacts, the tunneling transistors based on WS<sub>2</sub>/SnS<sub>2</sub> van der Waals heterostructures are experimentally demonstrated with Pt as the source contact and Ti as the drain contact, and electrical characterization at different temperatures and under different bias conditions are performed. The thicknesses of the WS<sub>2</sub> flakes are designed according to the above contact optimization, and are measured to be 23 nm by AFM. In contrast, the contact resistance of n-type metal-to-SnS<sub>2</sub> is thicknesses insensitive due to the nearly unchanged position of conduction band when layer number increases, and the SnS<sub>2</sub> used in tunneling transistor is measured to be 4 nm. Figure 4a shows the measured typical transfer characteristics of the n-type WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistor at room temperature. The results are obtained by applying the bias on SnS<sub>2</sub> contact, with WS<sub>2</sub> contact grounded. With the optimized design of metal-to-2D semiconductor contacts, the n-type WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistor exhibits high  $I_{ON}$  of  $3.7 \mu\text{A}$ . The on/off current ratio of the fabricated device is over  $10^6$  and the on-state current density is  $186 \text{ nA } \mu\text{m}^{-2}$ . The high on/off current ratio, and high on-state current which is comparable with the value obtained in the SnS<sub>2</sub> SB-FET, further confirm the optimized band alignment in WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistors. Compared with conventional SB-FET in Fig. 2b, the subthreshold slope of the fabricated WS<sub>2</sub>/SnS<sub>2</sub> device is much steeper and also increases with gate voltage which is a typical feature of tunnel



**Figure 4.** Electrical characteristics of the WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistor. (a) Measured transfer characteristics of the bottom-gated WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistor. The on-state current ( $I_{ON}$ ) is 3.7  $\mu$ A with an area of 20  $\mu$ m<sup>2</sup> and on/off current ratio is over  $10^6$ . (b) Measured temperature characteristics of the bottom-gated WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistor.

transistors. Since the transistor is fabricated based on bottom-gated structure with 300 nm-thick SiO<sub>2</sub>, the value of SS is relatively large, and can be further optimized by reducing the gate oxide thickness or incorporating with high- $\kappa$  dielectrics. In order to further verify the BTBT mechanism of this n-type transistor, the dependence of transfer characteristics on temperature is studied. As shown in Fig. 4b,  $I_{ON}$  shows the positive dependence on temperature and SS changes little with temperature, exhibiting the typical features of BTBT operation mechanism<sup>35–38</sup>. The weak dependence of SS on temperature also indicates the suppression of trap-assisted tunneling, which benefits from the clean interface obtained from the dry transfer process.

In order to further validate the BTBT mechanism in this WS<sub>2</sub>/SnS<sub>2</sub> heterostructure, the output characteristics in forward bias region are investigated. Figure 5a shows the output characteristics at 100 K, which are measured by applying the voltage on WS<sub>2</sub> contact, with SnS<sub>2</sub> contact grounded. The distinct negative differential resistance (NDR) is observed and confirms that a heavily-doped p-n junction is formed at the interface due to charge transfer<sup>17</sup>. The band alignments of the WS<sub>2</sub>/SnS<sub>2</sub> heterostructure under different bias conditions are illustrated in Fig. 5b–e. In the equilibrium state, the Fermi level in p-WS<sub>2</sub> and n-SnS<sub>2</sub> is aligned, as shown in Fig. 5b. As the source-drain voltage  $V_{SD}$  increases, the energy band of WS<sub>2</sub> is pulled down and a finite tunneling window is created for electrons in the conduction band of SnS<sub>2</sub> to tunnel into the empty states in the valence band of WS<sub>2</sub>. The tunnel current reaches its peak when the Fermi level of WS<sub>2</sub> aligns with the conduction band minimum of SnS<sub>2</sub>, as shown in Fig. 5c. With  $V_{SD}$  further increasing, the tunneling window is gradually switched off and the reduction of tunnel current leads to NDR (Fig. 5d). After that, thermal injection current begins to dominate the



**Figure 5.** Negative differential resistance (NDR) feature of the  $\text{WS}_2/\text{SnS}_2$  tunneling transistor. **(a)** Measured output characteristics of the bottom-gated  $\text{WS}_2/\text{SnS}_2$  tunneling transistor in the forward bias region. Clear NDR is observed for positive gate voltages. **(b)** Band alignment at  $V_{\text{SD}} = 0$  V. Fermi level in  $\text{WS}_2$  and  $\text{SnS}_2$  is aligned. **(c)** Band alignment at  $V_{\text{SD}} > 0$  V. The band of p-type  $\text{WS}_2$  is pulled down and a finite tunneling window is created for electrons in the conduction band of  $\text{SnS}_2$  to tunnel into the empty states in the valence band of  $\text{WS}_2$ . The tunnel current reaches its peak when the Fermi level of  $\text{WS}_2$  aligns with the conduction band minimum of  $\text{SnS}_2$ . With further increasing  $V_{\text{SD}}$  **(d)**, the tunnel window is gradually switched off and the reduction of tunnel current leads to NDR. When  $V_{\text{SD}}$  continues to increase **(e)**, the thermal injection current dominates and increases with the reduced energy barrier.

total current due to the reduced thermal barrier, and increases with  $V_{\text{SD}}$  (Fig. 5e). It should be noted that the peak voltage can be modulated by the bottom-gate voltage  $V_{\text{BG}}$  in this device. The conduction band of  $\text{SnS}_2$  varies with  $V_{\text{BG}}$ , and the peak voltage needed to align the Fermi level of  $\text{WS}_2$  with the conduction band of  $\text{SnS}_2$  changes consequently.

## Conclusions

In conclusion, the optimal  $\text{WS}_2/\text{SnS}_2$  van der Waals heterostructure for tunneling transistors is presented and elaborately engineered, taking into consideration both electric properties and material stability. Besides, the key challenge of metal-to-2D semiconductor contact is optimized to achieve low-resistance n-type and p-type contacts for  $\text{SnS}_2$  and  $\text{WS}_2$ , respectively. Ti contact with low work function and superior stability can induce small Schottky barrier height for electrons at metal-to- $\text{SnS}_2$  contacts. Low-resistance p-type contacts are obtained at the metal/ $\text{WS}_2$  interface through the thickness optimization of  $\text{WS}_2$ . With the optimized metal-to-2D semiconductor contacts and a proposed new dry transfer technique for vertical heterostructure stack, the fabricated n-type  $\text{WS}_2/\text{SnS}_2$  tunneling transistor exhibits superior performance with the high on/off current ratio over  $10^6$ , as well as comparable on-state current and steeper subthreshold slope compared with conventional FET, showing the great potential of van der Waals heterostructure for future energy-efficient devices.

## Methods

**Device Fabrication.** The highly n-type Si substrate with 300 nm thermal silicon oxide is prepared as the bottom gate structure. The starting materials used for the fabrication of n-type WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistors were high-quality bulk crystals of WS<sub>2</sub> and SnS<sub>2</sub>. The process flow of the bottom-gated WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistor has been described in the Supplementary Fig. S1. In details, 10 nm Ti/20 nm Au was deposited to form the Ti-to-SnS<sub>2</sub> contact, and the Pt-to-WS<sub>2</sub> contact was generated with 20 nm Pt/40 nm Au.

**Physical Characterization.** AFM and Raman spectra were used to characterize the thicknesses of WS<sub>2</sub> and SnS<sub>2</sub>. Raman spectra were excited by 514 nm laser with the spot diameter about 1 μm. The laser power was kept less than 0.1 mW to avoid sample heating and oxidation in the air. Structural characterization by scanning TEM (STEM) was performed in JEM-ARM200F with the acceleration voltage of 100 keV. The STEM sample was prepared by focused ion beam (FIB) using the gallium beam.

**Electrical Measurements.** N-type WS<sub>2</sub>/SnS<sub>2</sub> tunneling transistors were electrically characterized in the vacuum chamber using the Agilent B1500A semiconductor parameter analyzer.

## Data Availability

All data supporting this study and its findings are available within the article, its Supplementary Information and associated files. Any source data deemed relevant is available from the corresponding author upon request.

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### Acknowledgements

This work was partly supported by NSFC (61421005, 61822401 & 61604006) and the 111 Project (B18001). The authors would like to thank the staff of National Center for Nanoscience and Technology for their assistance in the electron beam lithography during device fabrication.

### Author Contributions

J.X.W., Q.Q.H. and R.H. conceived the research. J.X.W. designed the experiment. J.X.W. and R.D.J. performed most of the experiments including device fabrication, characterization and data analysis. P.C. and F.M. performed the transfer of the heterostructure. J.D.Z., H.M.W., C.C., Y.W.Z., Y.C.Y. and F.M. offered useful discussions and essential recommendations about the data analysis and paper-writing. H.S.S. synthesized the SnS<sub>2</sub> samples. R.H. supervised the research. R.D.J. and Q.Q.H. co-wrote the paper.

### Additional Information

**Supplementary information** accompanies this paper at <https://doi.org/10.1038/s41598-018-35661-4>.

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